

Title (en)
A FILM DEPOSITING APPARATUS AND METHOD

Title (de)
FILMABLAGERUNGSVORRICHTUNG UND -VERFAHREN

Title (fr)
APPAREIL ET PROCÉDÉ DE DÉPÔT DE FILM

Publication
EP 2304071 A4 20120307 (EN)

Application
EP 09803066 A 20090729

Priority
• JP 2009063829 W 20090729
• JP 2008197939 A 20080731

Abstract (en)
[origin: WO2010013831A1] A film depositing apparatus comprises: a vacuum vessel; an evacuating unit for evacuating the interior of the vacuum vessel; a gas supply source for supplying the vacuum vessel with gases necessary for film deposition; a backing plate that is placed within the vacuum vessel for holding a target formed by sintering; a substrate holder for holding a deposition substrate within the vacuum vessel in a face-to-face relation with the backing plate; and a power supply unit for supplying electric power between the backing plate and the substrate holder to generate a plasma within the vacuum vessel, wherein the backing plate has a smaller thermal expansion coefficient than that of the target which has a sinter density of at least 95%, the sinter density representing the ratio of the actual weight of a sintered form of the target to its theoretical weight.

IPC 8 full level
C23C 14/34 (2006.01); **H01J 37/34** (2006.01); **H01L 21/28** (2006.01); **H01L 21/285** (2006.01)

CPC (source: EP US)
C23C 14/088 (2013.01 - EP US); **C23C 14/3414** (2013.01 - EP US); **H01J 37/3426** (2013.01 - EP US); **H01J 37/3435** (2013.01 - EP US); **H01L 21/67103** (2013.01 - EP US)

Citation (search report)
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• [A] WO 2004065046 A2 20040805 - TOSOH SMD INC [US], et al
• [Y] EP 1452490 A1 20040901 - MATSUSHITA ELECTRIC IND CO LTD [JP]
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• See references of WO 2010013831A1

Designated contracting state (EPC)
AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO SE SI SK SM TR

DOCDB simple family (publication)
WO 2010013831 A1 20100204; EP 2304071 A1 20110406; EP 2304071 A4 20120307; JP 2010037565 A 20100218; JP 5344864 B2 20131120; US 2011014394 A1 20110120

DOCDB simple family (application)
JP 2009063829 W 20090729; EP 09803066 A 20090729; JP 2008197939 A 20080731; US 66742909 A 20090729